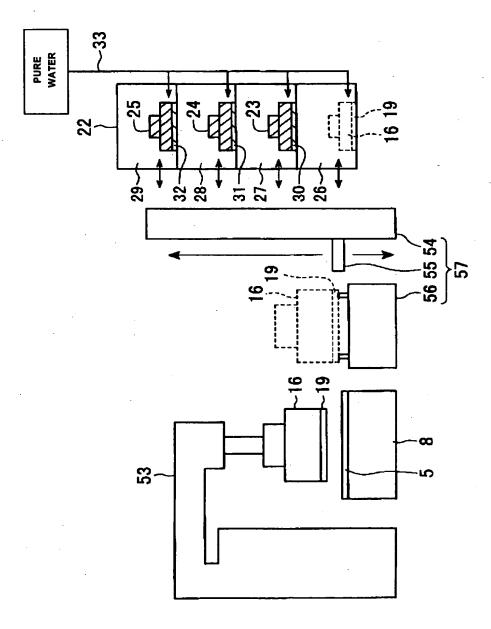
Title: CMP APPARATUS, CMP POLISHING METHOD, SEMICONDUCTOR DEVICE AND ITS MANUFACTURING METHOD

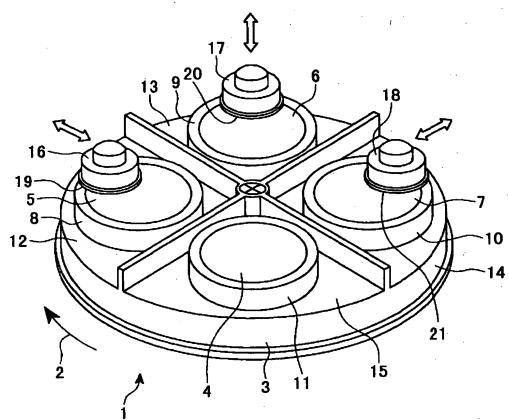
Inventor: Junichi TAKEUCHI Atty. Ref.: 9319S-000690

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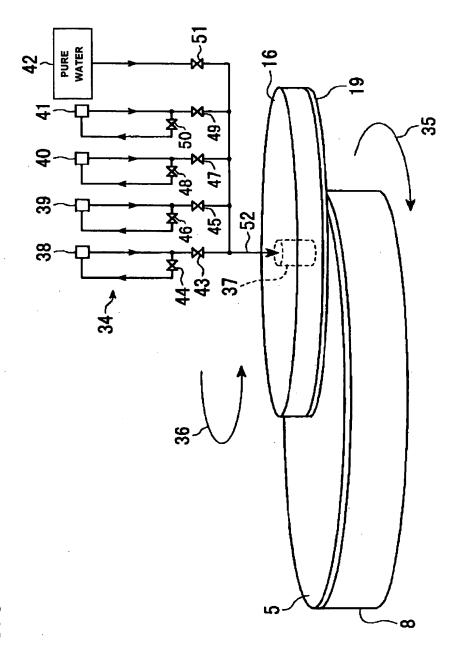
FIG. 2



Title: CMP APPARATUS, CMP POLISHING METHOD, SEMICONDUCTOR DEVICE AND ITS MANUFACTURING METHOD

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<u>FIG. 3</u>

MANUFACTURING METHOD Inventor: Junichi TAKEUCHI Atty. Ref.: 9319S-000690

FIG. 4 PRIOR ART



